

WEST Search History

DATE: Sunday, May 11, 2008

<u>Hide?</u>	<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>
<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=OR</i>			
<input type="checkbox"/>	L15	(L3 or L4) and (MEMS or microelectromechanical or micro-electro-mechanical).clm.	192
<input type="checkbox"/>	L14	L13 not (L11 or L8 or L6 or L2)	1930
<input type="checkbox"/>	L13	L12 and (bond\$3 with (wafer or substrate))	2529
<input type="checkbox"/>	L12	MEMS same actuator	18777
<input type="checkbox"/>	L11	L10 and actuat\$5	632
<input type="checkbox"/>	L10	L9 and ((recess\$3 or cavit\$4) with (substrate or wafer))	3124
<input type="checkbox"/>	L9	(second with (wafer or substrate)) and (first with (wafer or substrate)) and ((groove or opening or slot or vent) with bond\$3)	11735
<input type="checkbox"/>	L8	L7 not L6	51
<input type="checkbox"/>	L7	(L3 or L4) and (((entrap\$5 or trap\$4 or releas\$3) with (air or gas)) same bond\$3)	77
<input type="checkbox"/>	L6	(L3 or L4) and (micro-mechanical\$4 or MEMS or micromechanical\$4 or micro-electro-mechanical)	778
<input type="checkbox"/>	L5	(L3 or L4) and (micro-mechanical\$4 or MEMS or micromechanical\$4)	775
<input type="checkbox"/>	L4	438/106,107,456.ccls.	5797
<input type="checkbox"/>	L3	359/223.ccls.	1128
<input type="checkbox"/>	L2	L1 and (bond\$3 with (wafer or substrate))	1057
<input type="checkbox"/>	L1	(optical adj switch) and MEMS	4430

END OF SEARCH HISTORY